NON-PLANAR DIRECT-WRITE NANOLITHOGRAPHY

HARDWARE, CIRCUITS, & SENSORS
Method for direct-write nanolithography on non-planar surfaces for high-resolution, precise patterns at lower costs than convention methods.

TECHNOLOGY TYPE
Manufacturing

STAGE OF DEVELOPMENT
Established proof of concept.

IP PROTECTION
Provisional patent filed.

LEARN MORE
Reference Number: U-6774

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TECHNOLOGY SUMMARY
Available electrospinning technologies deposit haphazard fiber patterns. This deposition process significantly limits the pattern resolution and prohibits alignment between multiple layers.

University of Utah researchers have developed a method of direct-writing nanofibers and nanoparticles that enables the production of high-resolution, precise patterns. This technology is not only less expensive than current deposition technologies, but also enables direct-writing onto non-planar, or curved, surfaces.

FEATURES AND BENEFITS
• Less expensive than current technologies.
• Enables direct-writing onto non-planar surfaces.
• Facilitates precise patterning for high-resolution products.

RECENT PUBLICATIONS

INVENTOR PROFILE
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